

Connecting via Winsock to STN

Welcome to STN International! Enter x:x

LOGINID:ssptasmb1637

PASSWORD:

TERMINAL (ENTER 1, 2, 3, OR ?):2

***** Welcome to STN International *****

NEWS	1		Web Page for STN Seminar Schedule - N. America
NEWS	2	JAN 02	STN pricing information for 2008 now available
NEWS	3	JAN 16	CAS patent coverage enhanced to include exemplified prophetic substances
NEWS	4	JAN 28	USPATFULL, USPAT2, and USPATOLD enhanced with new custom IPC display formats
NEWS	5	JAN 28	MARPAT searching enhanced
NEWS	6	JAN 28	USGENE now provides USPTO sequence data within 3 days of publication
NEWS	7	JAN 28	TOXCENTER enhanced with reloaded MEDLINE segment
NEWS	8	JAN 28	MEDLINE and LMEEDLINE reloaded with enhancements
NEWS	9	FEB 08	STN Express, Version 8.3, now available
NEWS	10	FEB 20	PCI now available as a replacement to DPCI
NEWS	11	FEB 25	IFIREF reloaded with enhancements
NEWS	12	FEB 25	IMSPRODUCT reloaded with enhancements
NEWS	13	FEB 29	WPINDEX/WPIDS/WPIX enhanced with ECLA and current U.S. National Patent Classification
NEWS	14	MAR 31	IFICDB, IFIPAT, and IFIUDB enhanced with new custom IPC display formats
NEWS	15	MAR 31	CAS REGISTRY enhanced with additional experimental spectra
NEWS	16	MAR 31	CA/CAPLUS and CASREACT patent number format for U.S. applications updated
NEWS	17	MAR 31	LPCI now available as a replacement to LDPCI
NEWS	18	MAR 31	EMBASE, EMBAL, and LEMBASE reloaded with enhancements
NEWS	19	APR 04	STN AnaVist, Version 1, to be discontinued
NEWS	20	APR 15	WPIDS, WPINDEX, and WPIX enhanced with new predefined hit display formats
NEWS	21	APR 28	EMBASE Controlled Term thesaurus enhanced
NEWS	22	APR 28	IMSRESEARCH reloaded with enhancements
NEWS	23	MAY 30	INPAFAMDB now available on STN for patent family searching
NEWS	24	MAY 30	DGENE, PCTGEN, and USGENE enhanced with new homology sequence search option
NEWS	25	JUN 06	EPFULL enhanced with 260,000 English abstracts
NEWS	26	JUN 06	KOREAPAT updated with 41,000 documents
NEWS EXPRESS	FEBRUARY 08 CURRENT WINDOWS VERSION IS V8.3, AND CURRENT DISCOVER FILE IS DATED 20 FEBRUARY 2008		
NEWS HOURS	STN Operating Hours Plus Help Desk Availability		
NEWS LOGIN	Welcome Banner and News Items		
NEWS IPC8	For general information regarding STN implementation of IPC 8		

Enter NEWS followed by the item number or name to see news on that specific topic.

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* * * * * STN Columbus * * * * *

FILE 'HOME' ENTERED AT 15:58:27 ON 11 JUN 2008

=> file registry

COST IN U.S. DOLLARS

SINCE FILE

TOTAL

ENTRY

SESSION

FULL ESTIMATED COST

0.21

0.21

FILE 'REGISTRY' ENTERED AT 15:59:09 ON 11 JUN 2008

USE IS SUBJECT TO THE TERMS OF YOUR STN CUSTOMER AGREEMENT.

PLEASE SEE "HELP USAGETERMS" FOR DETAILS.

COPYRIGHT (C) 2008 American Chemical Society (ACS)

Property values tagged with IC are from the ZIC/VINITI data file provided by InfoChem.

STRUCTURE FILE UPDATES: 10 JUN 2008 HIGHEST RN 1027136-44-2

DICTIONARY FILE UPDATES: 10 JUN 2008 HIGHEST RN 1027136-44-2

New CAS Information Use Policies, enter HELP USAGETERMS for details.

TSCA INFORMATION NOW CURRENT THROUGH January 9, 2008.

Please note that search-term pricing does apply when conducting SmartSELECT searches.

REGISTRY includes numerically searchable data for experimental and predicted properties as well as tags indicating availability of experimental property data in the original document. For information on property searching in REGISTRY, refer to:

<http://www.cas.org/support/stngen/stndoc/properties.html>

=>Testing the current file.... screen

ENTER SCREEN EXPRESSION OR (END):end

=>

Uploading C:\Program Files\Stnexp\Queries\10765366\str2d.str



```

chain nodes :
1 5
ring/chain nodes :
2 3 4 11 12
chain bonds :
1-2 4-5
ring/chain bonds :
2-3 2-11 2-12 3-4
exact/norm bonds :
2-3 2-11 2-12 3-4 4-5
exact bonds :
1-2

```

G1:CH3,CF3

Match level :

1:CLASS 2:CLASS 3:CLASS 4:CLASS 5:CLASS 11:CLASS 12:CLASS

L1 STRUCTURE UPLOADED

=> que L1

L2 QUE L1

=> s l1

SAMPLE SEARCH INITIATED 15:59:32 FILE 'REGISTRY'

SAMPLE SCREEN SEARCH COMPLETED - 562 TO ITERATE

100.0% PROCESSED 562 ITERATIONS

19 ANSWERS

SEARCH TIME: 00.00.01

FULL FILE PROJECTIONS: ONLINE **COMPLETE**

BATCH **COMPLETE**

PROJECTED ITERATIONS: 9818 TO 12662

PROJECTED ANSWERS: 119 TO 641

L3 19 SEA SSS SAM L1

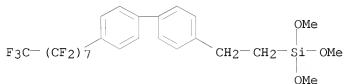
=> d scan 1

'1' IS NOT A VALID FORMAT FOR FILE 'REGISTRY'

L3 19 ANSWERS REGISTRY COPYRIGHT 2008 ACS on SIN

IN 1,1'-Biphenyl, 4-(1,1,2,2,3,3,4,4,5,5,6,6,7,7,8,8-heptafluorooctyl)-
4'-[2-(trimethoxysilyl)ethyl]-

MF C25 H21 F17 O3 Si



PROPERTY DATA AVAILABLE IN THE 'PROP' FORMAT

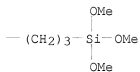
The following are valid formats:

Substance information can be displayed by requesting individual fields or predefined formats. The predefined substance formats are: (RN = CAS Registry Number)

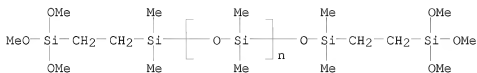
REG - RN
SAM - Index Name, MF, and structure - no RN
FIDE - All substance data, except sequence data
IDE - FIDE, but only 50 names
SQIDE - IDE, plus sequence data
SQIDE3 - Same as SQIDE, but 3-letter amino acid codes are used
SQD - Protein sequence data, includes RN
SQD3 - Same as SQD, but 3-letter amino acid codes are used
SQN - Protein sequence name information, includes RN

CALC - Table of calculated properties
EPROP - Table of experimental properties
PROP - EPROP and CALC

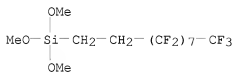
Any CA File format may be combined with any substance format to obtain CA references citing the substance. The substance formats must be cited first. The CA File predefined formats are:



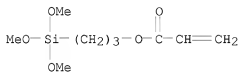
CM 2



CM 3



CM 4



HOW MANY MORE ANSWERS DO YOU WISH TO SCAN? (1):

HOW MANY MORE ANSWERS DO YOU WISH TO SCAN? (1):0

=> s l1 ful

FULL SEARCH INITIATED 16:00:06 FILE 'REGISTRY'

FULL SCREEN SEARCH COMPLETED - 10724 TO ITERATE

100.0% PROCESSED 10724 ITERATIONS

329 ANSWERS

SEARCH TIME: 00.00.01

L4

329 SEA SSS FUL L1

=>Testing the current file.... screen

ENTER SCREEN EXPRESSION OR (END):end

=> screen 965

L5 SCREEN CREATED

=>

Uploading C:\Program Files\Stnexp\Queries\10765366\str2c.str



chain nodes :

1 2 3 4 5 6 7

chain bonds :

1-2 2-3 2-6 2-7 3-4 4-5

exact/norm bonds :

4-5

exact bonds :

1-2 2-3 2-6 2-7 3-4

G1:CH3,CF3

Match level :

1:CLASS 2:CLASS 3:CLASS 4:CLASS 5:CLASS 6:CLASS 7:CLASS

L6 STRUCTURE UPLOADED

=> que L6 AND L5

L7 QUE L6 AND L5

=> s l7 ful

FULL SEARCH INITIATED 16:00:38 FILE 'REGISTRY'

FULL SCREEN SEARCH COMPLETED - 3302 TO ITERATE

100.0% PROCESSED 3302 ITERATIONS

196 ANSWERS

SEARCH TIME: 00.00.01

L8 196 SEA SSS FUL L6 AND L5

=> s l4 or l8

L9 525 L4 OR L8

=>Testing the current file.... screen

ENTER SCREEN EXPRESSION OR (END):end

=> screen 965

L10 SCREEN CREATED

=>

Uploading C:\Program Files\Stnexp\Queries\10765366\strld.str



chain nodes :

1

ring/chain nodes :

2 3 4 7 8

chain bonds :

1-2

ring/chain bonds :

2-3 2-7 2-8 3-4

exact/norm bonds :

2-3 2-7 2-8 3-4

exact bonds :

1-2

Match level :

1:CLASS 2:CLASS 3:CLASS 4:CLASS 7:CLASS 8:CLASS

L11 STRUCTURE UPLOADED

=> que L11 AND L10

L12 QUE L11 AND L10

=> s l12 ful

FULL SEARCH INITIATED 16:01:08 FILE 'REGISTRY'

FULL SCREEN SEARCH COMPLETED - 89633 TO ITERATE

100.0% PROCESSED 89633 ITERATIONS

12873 ANSWERS

SEARCH TIME: 00.00.01

L13 12873 SEA SSS FUL L11 AND L10

=>Testing the current file.... screen

ENTER SCREEN EXPRESSION OR (END):end

=> screen 965

L14 SCREEN CREATED

=>

Uploading C:\Program Files\Stnexp\Queries\10765366\strld.str



chain nodes :

1

ring/chain nodes :

2 3 4 7 8

chain bonds :

1-2

ring/chain bonds :

2-3 2-7 2-8 3-4

exact/norm bonds :

2-3 2-7 2-8 3-4

exact bonds :

1-2

Match level :

1:CLASS 2:CLASS 3:CLASS 4:CLASS 7:CLASS 8:CLASS

L15 STRUCTURE UPLOADED

=> que L15 AND L14

L16 QUE L15 AND L14

=> s l16 ful

FULL SEARCH INITIATED 16:01:30 FILE 'REGISTRY'

FULL SCREEN SEARCH COMPLETED - 89633 TO ITERATE

100.0% PROCESSED 89633 ITERATIONS

12873 ANSWERS

SEARCH TIME: 00.00.01

L17 12873 SEA SSS FUL L15 AND L14

=> s l13 or l17

L18 12873 L13 OR L17

=> s l18 and l9

L19 229 L18 AND L9

=> file caplus

COST IN U.S. DOLLARS

SINCE FILE

TOTAL

ENTRY

SESSION

FULL ESTIMATED COST

713.90

714.11

FILE 'CAPLUS' ENTERED AT 16:02:05 ON 11 JUN 2008

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FILE COVERS 1907 - 11 Jun 2008 VOL 148 ISS 24

FILE LAST UPDATED: 10 Jun 2008 (20080610/ED)

Effective October 17, 2005, revised CAS Information Use Policies apply. They are available for your review at:

<http://www.cas.org/legal/infopolicy.html>

=> s l19

L20 795 L19

=> dup remove l20

PROCESSING COMPLETED FOR L20

L21 794 DUP REMOVE L20 (1 DUPLICATE REMOVED)

=> s l21 and silicon

L22 794 S L21

883161 SILICON

421 SILICONS

883305 SILICON

(SILICON OR SILICONS)

L23 140 L22 AND SILICON

=> dup remove l23

PROCESSING COMPLETED FOR L23

L24 140 DUP REMOVE L23 (0 DUPLICATES REMOVED)

=> s l24 and (vapor or cvd or pecvd)

L25 140 S L24

564157 VAPOR

74017 VAPORS

607606 VAPOR

(VAPOR OR VAPORS)

76827 CVD
83 CVDS
76848 CVD
(CVD OR CVDS)

8624 PECVD
L26 25 L25 AND (VAPOR OR CVD OR PECVD)

=> dup remove l26

PROCESSING COMPLETED FOR L26

L27 25 DUP REMOVE L26 (0 DUPLICATES REMOVED)

=> d ti 1-25

L27 ANSWER 1 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
TI Layer-by-layer fabrication of broad-band super-hydrophobic antireflection coatings in near-infrared region

L27 ANSWER 2 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
TI Digital magnetofluidic devices and methods

L27 ANSWER 3 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
TI Method of processing a biological and/or chemical sample

L27 ANSWER 4 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
TI Thin organic alignment layers with a batch process for liquid crystal displays

L27 ANSWER 5 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
TI Atmospheric plasma deposition of hydrophobic/oil-repellent coatings with improved durability on glass/ceramic windows

L27 ANSWER 6 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
TI Method for constructing surface enhanced substrate with metal ordered structure

L27 ANSWER 7 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
TI Method for identical dye molecule emitting different color fluorescent light by substrate induction

L27 ANSWER 8 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
TI Surface engineering of poly(dimethylsiloxane) micro fluidic devices using transition metal sol-gel chemistry

L27 ANSWER 9 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
TI Thermal stability of vapor phase deposited self-assembled monolayers for MEMS anti-stiction

L27 ANSWER 10 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
TI Surface modification of silicon and polydimethylsiloxane surfaces with vapor-phase-deposited ultrathin fluorosilane films for biomedical nanodevices

L27 ANSWER 11 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
TI Rain-proof glass windows with a silicon-containing hydrophobic surface of improved durability

L27 ANSWER 12 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
TI Micropatterning of SrBi₂Ta₂O₉ ferroelectric thin films using a selective deposition technique combined with patterned self-assembled monolayers and liquid-source misted chemical deposition

L27 ANSWER 13 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN

TI Nanoscale patterning of protein using electron beam lithography of organosilane self-assembled monolayers

L27 ANSWER 14 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
 TI Liquid and vapor phase silanes coating for the release of thin film MEMS

L27 ANSWER 15 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
 TI Thin film forming method and thin film forming substance

L27 ANSWER 16 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
 TI Method of coating microelectromechanical devices

L27 ANSWER 17 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
 TI Method and apparatus for manufacturing anti-reflective films

L27 ANSWER 18 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
 TI Vapor pressures of precursors for the CVD of silicon-based films

L27 ANSWER 19 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
 TI Self-assembled monolayer coatings on nanostencils for the reduction of materials adhesion

L27 ANSWER 20 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
 TI Method for making thin film and electronic apparatus

L27 ANSWER 21 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
 TI Formation method of silicon thin film

L27 ANSWER 22 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
 TI Method for providing water-repellent coatings on optical substrates

L27 ANSWER 23 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
 TI Vapor Phase Self-Assembly of Fluorinated Monolayers on Silicon and Germanium Oxide

L27 ANSWER 24 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
 TI Water-repellent fluorine-containing silicon oxide coatings

L27 ANSWER 25 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
 TI Heat- and chemical-resistant organic thin films and their manufacture

=> d bib 1-25

L27 ANSWER 1 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
 AN 2008:78111 CAPLUS
 DN 148:333398
 TI Layer-by-layer fabrication of broad-band super-hydrophobic antireflection coatings in near-infrared region
 AU Zhang, Lianbin; Li, Yang; Sun, Junqi; Shen, Jiacong
 CS State Key Lab of Supramolecular Structure and Materials, College of Chemistry, Jilin University, Changchun, 130012, Peop. Rep. China
 SO Journal of Colloid and Interface Science (2008), 319(1), 302-308
 CODEN: JCISA5; ISSN: 0021-9797
 PB Elsevier
 DT Journal
 LA English
 RE.CNT 49 THERE ARE 49 CITED REFERENCES AVAILABLE FOR THIS RECORD
 ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 2 OF 25 CAPLUS COPYRIGHT 2008 ACS ON STN
 AN 2007:1000213 CAPLUS
 DN 147:355832
 TI Digital magnetofluidic devices and methods
 IN Hernandez, Sonia Melle; Gomez, Ana N.; Picraux, S. Thomas; Gust, John
 Devens; Hayes, Mark; Lindsay, Solitaire; Garcia, Antonio A.; Wang, Joseph;
 Vazquez-Alvarez, Terannie
 PA Arizona Board of Regents for and on Behalf of Arizona State University,
 USA
 SO PCT Int. Appl., 118pp.
 CODEN: P1XXD2
 DT Patent
 LA English
 FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	WO 2007101174	A2	20070907	WO 2007-US62842	20070227
	WO 2007101174	A3	20071221		
	W:	AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BR, BW, BY, BZ, CA, CH, CN, CO, CR, CU, CZ, DE, DK, DM, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, GT, HN, HR, HU, ID, IL, IN, IS, JP, KE, KG, KM, KN, KP, KR, KZ, LA, LC, LK, LR, LS, LT, LU, LV, LY, MA, MD, MG, MK, MN, MW, MX, MY, MZ, NA, NG, NI, NO, NZ, OM, PG, PH, PL, PT, RO, RS, RU, SC, SD, SE, SG, SK, SL, SM, SV, SY, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, ZA, ZM, ZW			
	RW:	AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE, IS, IT, LT, LU, LV, MC, NL, PL, PT, RO, SE, SI, SK, TR, BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE, SN, TD, TG, BW, GH, GM, KE, LS, MW, MZ, NA, SD, SL, SZ, TZ, UG, ZM, ZW, AM, AZ, BY, KG, KZ, MD, RU, TJ, TM, AP, EA, EP, OA			

PRAI US 2006-777679P P 20060227

L27 ANSWER 3 OF 25 CAPLUS COPYRIGHT 2008 ACS ON STN
 AN 2007:933138 CAPLUS
 DN 147:290978
 TI Method of processing a biological and/or chemical sample
 IN Pipper, Juergen; Hsieh, Tseng-Ming; Neuzil, Pavel
 PA Agency for Science, Technology and Research, Singapore
 SO PCT Int. Appl., 67pp.
 CODEN: P1XXD2
 DT Patent
 LA English
 FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	WO 2007094739	A1	20070823	WO 2006-SG29	20060213
	W:	AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BR, BW, BY, BZ, CA, CH, CN, CO, CR, CU, CZ, DE, DK, DM, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, HR, HU, ID, IL, IN, IS, JP, KE, KG, KM, KN, KP, KR, KZ, LC, LK, LR, LS, LT, LU, LV, LY, MA, MD, MG, MK, MN, MW, MX, MZ, NA, NG, NI, NO, NZ, OM, PG, PH, PL, PT, RO, RU, SC, SD, SE, SG, SK, SL, SM, SY, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, YU, ZA, ZM, ZW			
	RW:	AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE, IS, IT, LT, LU, LV, MC, NL, PL, PT, RO, SE, SI, SK, TR, BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE, SN, TD, TG, BW, GH, GM, KE, LS, MW, MZ, NA, SD, SL, SZ, TZ, UG, ZM, ZW, AM, AZ, BY, KG, KZ, MD, RU, TJ, TM			

PRAI WO 2006-SG29 20060213

RE.CNT 5 THERE ARE 5 CITED REFERENCES AVAILABLE FOR THIS RECORD
 ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 4 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
 AN 2007:970042 CAPLUS
 DN 147:288568
 TI Thin organic alignment layers with a batch process for liquid crystal displays
 IN Ong, Hiap L.
 PA Kyoritsu Optonics Co., Ltd., Taiwan
 SO U.S. Pat. Appl. Publ., 16pp., Cont.-in-part of U.S. Ser. No. 227,570.
 CODEN: USXXCO
 DT Patent
 LA English
 FAN.CNT 2

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	US 20070202253	A1	20070830	US 2006-607246	20061201
	US 20070059438	A1	20070315	US 2005-227570	20050915
	CN 101191198	A	20080604	CN 2007-10165733	20071106
PRAI	US 2005-227570	A2	20050915		
	US 2006-607246	A	20061201		

L27 ANSWER 5 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
 AN 2007:1449167 CAPLUS
 DN 148:83928
 TI Atmospheric plasma deposition of hydrophobic/oil-repellent coatings with improved durability on glass/ceramic windows
 IN Durandeau, Anne; Montigaud, Herve; Abbott, Fabrice; Huignard, Arnaud
 PA Saint-Gobain Glass France, Fr.
 SO Fr. Demande, 28pp.
 CODEN: FRXXBL
 DT Patent
 LA French
 FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	FR 2902422	A1	20071221	FR 2006-52159	20060616
	WO 2007144536	A1	20071221	WO 2007-FR51421	20070612
	W: AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BH, BR, BW, BY, BZ, CA, CH, CN, CO, CR, CU, CZ, DE, DK, DM, DO, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, GT, HN, HR, HU, ID, IL, IN, IS, JP, KE, KG, KM, KN, KP, KR, KZ, LA, LC, LK, LR, LS, LT, LU, LY, MA, MD, ME, MG, MK, MN, MW, MX, MY, MZ, NA, NG, NI, NO, NZ, OM, PG, PH, PL, PT, RO, RS, RU, SC, SD, SE, SG, SK, SL, SM, SV, SY, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, ZA, ZM, ZW RW: AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE, IS, IT, LT, LU, LV, MC, MT, NL, PL, PT, RO, SE, SI, SK, TR, BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE, SN, TD, TG, BW, GH, GM, KE, LS, MW, MZ, NA, SD, SL, SZ, TZ, UG, ZM, ZW, AM, AZ, BY, KG, KZ, MD, RU, TJ, TM				
PRAI	FR 2006-52159	A	20060616		

RE.CNT 3 THERE ARE 3 CITED REFERENCES AVAILABLE FOR THIS RECORD
 ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 6 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
 AN 2007:980718 CAPLUS
 DN 147:376451
 TI Method for constructing surface enhanced substrate with metal ordered structure
 IN Lu, Nan; Yang, Bingjie; Huang, Chunyu; Chi, Lifeng
 PA Jilin University, Peop. Rep. China
 SO Faming Zhuanli Shenqing Gongkai Shuomingshu, 30pp.
 CODEN: CNXXEV
 DT Patent

LA Chinese

FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	CN 101024483	A	20070829	CN 2007-10055453	20070327
PRAI	CN 2007-10055453		20070327		

L27 ANSWER 7 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN

AN 2006:1085199 CAPLUS

DN 146:35674

TI Method for identical dye molecule emitting different color fluorescent light by substrate induction

IN Lu, Nan; Hu, Wei; Hao, Juanyuan; Chi, Lifeng

PA Jilin University, Peop. Rep. China

SO Faming Zhuanli Shenqing Gongkai Shuomingshu, 24pp.

CODEN: CNXXEV

DT Patent

LA Chinese

FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	CN 1844300	A	20061011	CN 2006-10016744	20060404
PRAI	CN 2006-10016744		20060404		

L27 ANSWER 8 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN

AN 2006:277375 CAPLUS

DN 144:489687

TI Surface engineering of poly(dimethylsiloxane) micro fluidic devices using transition metal sol-gel chemistry

AU Roman, Gregory T.; Culbertson, Christopher T.

CS Department of Chemistry, Kansas State University, Manhattan, KS, 66506, USA

SO Langmuir (2006), 22(9), 4445-4451

CODEN: LANGD5; ISSN: 0743-7463

PB American Chemical Society

DT Journal

LA English

RE.CNT 86 THERE ARE 86 CITED REFERENCES AVAILABLE FOR THIS RECORD

ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 9 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN

AN 2006:1341743 CAPLUS

DN 147:475337

TI Thermal stability of vapor phase deposited self-assembled monolayers for MEMS anti-stiction

AU Zhuang, Yan Xin; Hansen, Ole; Knieling, Thomas; Wang, Christian; Rombach, Firmin; Lang, Walter; Benecke, Wolfgang; Kehlenbeck, Markus; Koblitz, Joern

CS CINF, MIC-Department of Micro and Nanotechnology, Technical University of Denmark, Lyngby, DK-2800, Den.

SO Journal of Micromechanics and Microengineering (2006), 16(11), 2259-2264

CODEN: JMMIEZ; ISSN: 0960-1317

PB Institute of Physics Publishing

DT Journal

LA English

RE.CNT 22 THERE ARE 22 CITED REFERENCES AVAILABLE FOR THIS RECORD

ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 10 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN

AN 2006:641508 CAPLUS

DN 145:183229

TI Surface modification of silicon and polydimethylsiloxane

surfaces with vapor-phase-deposited ultrathin fluorosilane films for biomedical nanodevices

AU Bhushan, Bharat; Hansford, Derek; Lee, Kang Kug

CS Nanotribology Laboratory for Information Storage and MEMS/NEMS, The Ohio State University, Columbus, OH, 43202, USA

SO Journal of Vacuum Science & Technology, A: Vacuum, Surfaces, and Films (2006), 24(4), 1197-1202

CODEN: JVIAD6; ISSN: 0734-2101

PB American Institute of Physics

DT Journal

LA English

RE.CNT 10 THERE ARE 10 CITED REFERENCES AVAILABLE FOR THIS RECORD

ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 11 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN

AN 2005:902015 CAPLUS

DN 143:233933

TI Rain-proof glass windows with a silicon-containing hydrophobic

surface of improved durability

IN Duran, Maxime; Huignard, Arnaud

PA Saint-Gobain Glass France, Fr.

SO Fr. Demande, 32 pp.

CODEN: FRXXBL

DT Patent

LA French

FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	FR 2866643	A1	20050826	FR 2004-50343	20040224
	FR 2866643	B1	20060526		
	WO 2005084943	A2	20050915	WO 2005-FR50119	20050223
	WO 2005084943	A3	20051103		
	W:	AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BR, BW, BY, BZ, CA, CH, CN, CO, CR, CU, CZ, DE, DK, DM, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, HR, HU, ID, IL, IN, IS, JP, KE, KG, KP, KR, KZ, LC, LK, LR, LS, LT, LU, LV, MA, MD, MG, MK, MN, MW, MX, MZ, NA, NI, NO, NZ, OM, PG, PH, PL, PT, RO, RU, SC, SD, SE, SG, SK, SL, SM, SY, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, YU, ZA, ZM, ZW			
	RW:	BW, GH, GM, KE, LS, MW, MZ, NA, SD, SL, SZ, TG, UG, ZM, ZW, AM, AZ, BY, KG, KZ, MD, RU, TJ, TM, AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE, IS, IT, LT, LU, MC, NL, PL, PT, RO, SE, SI, SK, TR, BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE, SN, TD, TG			
	EP 1720808	A2	20061115	EP 2005-728106	20050223
	R:	AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE, IS, IT, LI, LT, LU, MC, NL, PL, PT, RO, SE, SI, SK, TR			
	CN 1946646	A	20070411	CN 2005-80012900	20050223
	BR 2005007935	A	20070717	BR 2005-7935	20050223
	JP 2007523776	T	20070823	JP 2007-500274	20050223
	IN 2006KN02325	A	20070525	IN 2006-KN2325	20060817
	MX 2006PA09574	A	20061107	MX 2006-PA9574	20060823
PRAI	FR 2004-50343	A	20040224		
	WO 2005-FR50119	W	20050223		

RE.CNT 2 THERE ARE 2 CITED REFERENCES AVAILABLE FOR THIS RECORD

ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 12 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN

AN 2005:410625 CAPLUS

DN 143:88377

TI Micropatterning of SrBi2Ta2O9 ferroelectric thin films using a selective deposition technique combined with patterned self-assembled monolayers and liquid-source misted chemical deposition

AU Takakuwa, Atsushi; Ishida, Masaya; Shimoda, Tatsuya
 CS Technology Platform Research Center, SEIKO EPSON Corporation, Nagano,
 399-0293, Japan
 SO Japanese Journal of Applied Physics, Part 1: Regular Papers, Short Notes &
 Review Papers (2005), 44(4A), 1897-1900
 CODEN: JAPNDE
 PB Japan Society of Applied Physics
 DT Journal
 LA English
 RE.CNT 8 THERE ARE 8 CITED REFERENCES AVAILABLE FOR THIS RECORD
 ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 13 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
 AN 2005:702603 CAPLUS
 DN 144:208350
 TI Nanoscale patterning of protein using electron beam lithography of
 organosilane self-assembled monolayers
 AU Zhang, Guo-Jun; Tani, Takashi; Zako, Tamotsu; Hosaka, Takumi; Miyake,
 Takeo; Kanari, Yuzo; Funatsu, Takashi; Ohdomari, Iwao
 CS Nanotechnology Research Center and Institute of Biomedical Engineering,
 Waseda University, Tokyo, 162-0041, Japan
 SO Small (2005), 1(8-9), 833-837
 CODEN: SMALBC; ISSN: 1613-6810
 PB Wiley-VCH Verlag GmbH & Co. KGaA
 DT Journal
 LA English
 RE.CNT 22 THERE ARE 22 CITED REFERENCES AVAILABLE FOR THIS RECORD
 ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 14 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
 AN 2006:143210 CAPLUS
 DN 144:499593
 TI Liquid and vapor phase silanes coating for the release of thin
 film MEMS
 AU Parvais, B.; Pallandre, A.; Jonas, A. M.; Raskin, J.-P.
 CS Research Center in Micro and Nanoscopic Materials and Electronic Devices
 (CERMIN), Universite catholique de Louvain, Louvain-la-Neuve, B-1348,
 Belg.
 SO IEEE Trans. Device Mater. Reliab. (2005), 5(2), 250-254
 CODEN: ITDMA2; ISSN: 1530-4388
 URL: <http://ieeexplore.ieee.org/iel5/7298/31396/01458741.pdf?isnumber=31396&prod=JNL&arnumber=1458741&arSt=+250&ared=+254&arAuthor=Parvais%2C+B.%3B+Pallandre%2C+A.%3B+Jonas%2C+A.M.%3B+Raskin%2C+J.-P.>
 PB Institute of Electrical and Electronics Engineers
 DT Journal; (online computer file)
 LA English
 RE.CNT 18 THERE ARE 18 CITED REFERENCES AVAILABLE FOR THIS RECORD
 ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 15 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
 AN 2004:1060574 CAPLUS
 DN 142:40141
 TI Thin film forming method and thin film forming substance
 IN Kudo, Ichiro; Saito, Atsushi; Arita, Hiroaki
 PA Konica Minolta Holdings, Inc., Japan
 SO U.S. Pat. Appl. Publ., 32 pp.
 CODEN: USXXCO
 DT Patent
 LA English
 FAN.CNT 1

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
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PI US 20040247886 A1 20041209 US 2004-858704 20040601
 JP 2004360039 A 20041224 JP 2003-162032 20030606
 JP 2005023381 A 20050127 JP 2003-191025 20030703
 WO 2004108984 A1 20041216 WO 2004-JP7860 20040531
 W: AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BR, BW, BY, BZ, CA, CH,
 CN, CO, CR, CU, CZ, DE, DK, DM, DZ, EC, EE, EG, ES, FI, GB, GD,
 GE, GH, GM, GR, HU, ID, IL, IN, IS, KE, KG, KP, KR, KZ, LC, LR, LK,
 LR, LS, LT, LU, LV, MA, MD, MG, MK, MN, MW, MX, MZ, NA, NI, NO,
 NZ, OM, PG, PH, PL, PT, RO, RU, SC, SD, SE, SG, SK, SL, SY, TJ,
 TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, YU, ZA, ZM, ZW
 RW: BW, GH, GM, KE, LS, MW, MZ, NA, SD, SL, SZ, TZ, UG, ZM, ZW, AM,
 AZ, BY, KG, KZ, MD, RU, TJ, TM, AT, BE, BG, CH, CY, CZ, DE, DK,
 EE, ES, FI, FR, GB, GR, HU, IE, IT, LU, MC, NL, PL, PT, RO, SE,
 SI, SK, TR, BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE,
 SN, TD, TG
 EP 1643002 A1 20060405 EP 2004-735520 20040531
 R: AT, BE, CH, DE, DK, ES, FR, GB, GR, IT, LI, LU, NL, SE, MC, PT,
 IE, SI, LT, LV, FI, RO, MK, CY, AL, TR, BG, CZ, EE, HU, PL, SK, HR
 CN 1798865 A 20060705 20040531
 PRAI JP 2003-162032 A 20030606
 JP 2003-191025 A 20030703
 WO 2004-JP7860 W 20040531

L27 ANSWER 16 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN

AN 2004:162231 CAPLUS

DN 140:227524

TI Method of coating microelectromechanical devices

IN Yang, Zhihao

PA Eastman Kodak Company, USA

SO U.S. Pat. Appl. Publ., 7 pp.

CODEN: USXXCO

DT Patent

LA English

FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	US 20040037956	A1	20040226	US 2002-225846	20020822
	US 6808745	B2	20041026		
	EP 1416064	A2	20040506	EP 2003-77499	20030811
	EP 1416064	A3	20050615		
	EP 1416064	B1	20080507		
	R: AT, BE, CH, DE, DK, ES, FR, GB, GR, IT, LI, LU, NL, SE, MC, PT, IE, SI, LT, LV, FI, RO, MK, CY, AL, TR, BG, CZ, EE, HU, SK				
	JP 2004084073	A	20040318	JP 2003-298568	20030822
PRAI	US 2002-225846	A	20020822		

RE.CNT 7 THERE ARE 7 CITED REFERENCES AVAILABLE FOR THIS RECORD
 ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 17 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN

AN 2004:198553 CAPLUS

DN 140:236678

TI Method and apparatus for manufacturing anti-reflective films

IN Tanaka, Takeshi

PA Konica Minolta Holdings Inc., Japan

SO Jpn. Kokai Tokkyo Koho, 40 pp.

CODEN: JKXXAF

DT Patent

LA Japanese

FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	JP 2004075738	A	20040311	JP 2002-234607	20020812

PRAI JP 2002-234607

20020812

L27 ANSWER 18 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 2004:157226 CAPLUS
DN 140:383314
TI Vapor pressures of precursors for the CVD of
silicon-based films
AU Alcott, Gregory R.; van de Sanden, Richard M. C. M.; Kondic, Sascha;
Linden, Joannes L.
CS Department of Applied Physics, Eindhoven University of Technology,
Eindhoven, 5600 MB, Neth.
SO Chemical Vapor Deposition (2004), 10(1), 20-22
CODEN: CVDEFX; ISSN: 0948-1907
PB Wiley-VCH Verlag GmbH & Co. KGaA
DT Journal
LA English
RE.CNT 6 THERE ARE 6 CITED REFERENCES AVAILABLE FOR THIS RECORD
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 19 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 2003:256239 CAPLUS
DN 139:37976
TI Self-assembled monolayer coatings on nanostencils for the reduction of
materials adhesion
AU Kolbel, Marius; Tjerkstra, R. Willem; Kim, Gyuman; Brugger, Jurgen; van
Rijn, Cees J. M.; Nijdam, Wietze; Huskens, Jurriaan; Reinhoudt, David N.
CS Laboratory of Supramolecular Chemistry and Technology MESA+ Research
Institute, University of Twente, Enschede, NL-7500 AE, Neth.
SO Advanced Functional Materials (2003), 13(3), 219-224
CODEN: AFMDC6; ISSN: 1616-301X
PB Wiley-VCH Verlag GmbH & Co. KGaA
DT Journal
LA English
RE.CNT 17 THERE ARE 17 CITED REFERENCES AVAILABLE FOR THIS RECORD
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 20 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 2002:638152 CAPLUS
DN 137:177507
TI Method for making thin film and electronic apparatus
IN Furusawa, Masahiro; Shimoda, Tatsuya
PA Seiko Epson Corporation, Japan
SO U.S. Pat. Appl. Publ., 13 pp.
CODEN: USXXCO
DT Patent
LA English
FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
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PI	US 20020114887	A1	20020822	US 2001-26635	20011227
	US 6780465	B2	20040824		
	JP 2002275629	A	20020925	JP 2001-398535	20011227
PRAI JP	2000-403229	A	20001228		

RE.CNT 5 THERE ARE 5 CITED REFERENCES AVAILABLE FOR THIS RECORD
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 21 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 2002:539411 CAPLUS
DN 137:101690
TI Formation method of silicon thin film
IN Furusawa, Masahiro; Miyashita, Satoru; Yudasaka, Kazuo; Shimoda, Tatsuya;
Yokoyama, Yasuaki; Matsuki, Yasuo; Takeuchi, Yasumasa

PA Seiko Epson Corp., Japan; JSR Ltd.
SO Jpn. Kokai Tokkyo Koho, 7 pp.
CODEN: JKXXAF

DT Patent
LA Japanese

FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	JP 2002203794	A	20020719	JP 2000-402809	20001228
	JP 3745959	B2	20060215		
	US 20030087110	A1	20030508	US 2001-28712	20011228
	US 6846513	B2	20050125		
PRAI	JP 2000-402809	A	20001228		
OS	MARPAT 137:101690				

L27 ANSWER 22 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN

AN 1999:783781 CAPLUS

DN 132:37023

TI Method for providing water-repellent coatings on optical substrates

IN Anthes, Uwe; Dombrowski, Reiner

PA Merck Patent G.m.b.H., Germany

SO Eur. Pat. Appl., 8 pp.

CODEN: EPXXDW

DT Patent

LA German

FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	EP 962511	A1	19991208	EP 1999-110077	19990522
	EP 962511	B1	20051116		
	R: AT, BE, CH, DE, DK, ES, FR, GB, GR, IT, LI, LU, NL, SE, MC, PT, IE, SI, LT, LV, FI, RO				
	DE 19825100	A1	19991216	DE 1998-19825100	19980605
	ES 2252887	T3	20060516	ES 1999-110077	19990522
	JP 2000080331	A	20000321	JP 1999-153778	19990601
	JP 3549440	B2	20040804		
	KR 2000005904	A	20000125	KR 1999-20580	19990604
	US 6296793	B1	20011002	US 1999-325796	19990604
	US 20010033893	A1	20011025	US 2001-892712	20010628
PRAI	DE 1998-19825100	A	19980605		
	US 1999-325796	A3	19990604		

OS MARPAT 132:37023

RE.CNT 6 THERE ARE 6 CITED REFERENCES AVAILABLE FOR THIS RECORD
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 23 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN

AN 1997:178996 CAPLUS

DN 126:298032

OREF 126:57613a,57616a

TI Vapor Phase Self-Assembly of Fluorinated Monolayers on
Silicon and Germanium Oxide

AU Hoffmann, Patrick W.; Stelzle, Martin; Rabolt, John F.

CS IBM Almaden Research Center, San Jose, CA, 95120, USA

SO Langmuir (1997), 13(7), 1877-1880

CODEN: LANGD5; ISSN: 0743-7463

PB American Chemical Society

DT Journal

LA English

RE.CNT 21 THERE ARE 21 CITED REFERENCES AVAILABLE FOR THIS RECORD
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 24 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN

AN 1995:330786 CAPLUS
 DN 122:108850
 OREF 122:20441a,20444a
 TI Water-repellent fluorine-containing silicon oxide coatings
 IN Sumi, Toshio; Matsuda, Atsunori; Ogino, Etsuo; Soejima, Ayako
 PA Nippon Sheet Glass Co Ltd, Japan
 SO Jpn. Kokai Tokkyo Koho, 7 pp.
 CODEN: JKXXAF
 DT Patent
 LA Japanese
 FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
	-----	----	-----	-----	-----
PI	JP 06228755	A	19940816	JP 1993-16332	19930203
PRAI	JP 1993-16332		19930203		

L27 ANSWER 25 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
 AN 1994:109608 CAPLUS
 DN 120:109608
 OREF 120:19339a,19342a
 TI Heat- and chemical-resistant organic thin films and their manufacture
 IN Morikawa, Juko; Kasanuki, Juji; Yanagisawa, Yoshihiro; Matsuda, Hiroshi
 PA Canon Kk, Japan
 SO Jpn. Kokai Tokkyo Koho, 8 pp.
 CODEN: JKXXAF
 DT Patent
 LA Japanese
 FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
	-----	----	-----	-----	-----
PI	JP 05220887	A	19930831	JP 1992-28417	19920214
	JP 3025091	B2	20000327		
PRAI	JP 1992-28417		19920214		

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ALL L# QUERIES AND ANSWER SETS ARE DELETED AT LOGOFF

LOGOFF? (Y)/N/HOLD:y

COST IN U.S. DOLLARS

SINCE FILE

TOTAL

ENTRY

SESSION

FULL ESTIMATED COST

48.69

762.80

STN INTERNATIONAL LOGOFF AT 16:03:30 ON 11 JUN 2008